

**FIGURE 1B**

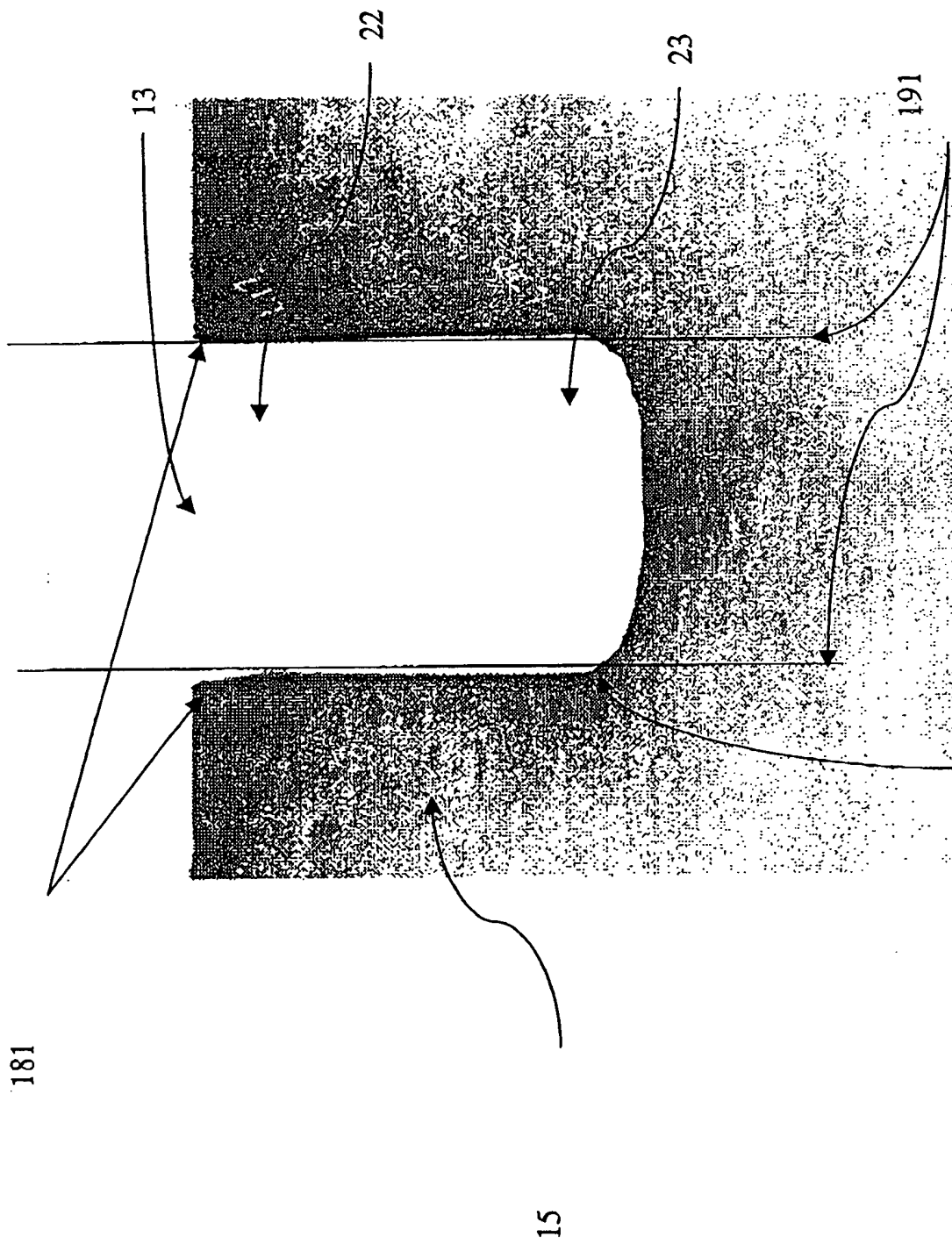


FIGURE 2

FIG. 3

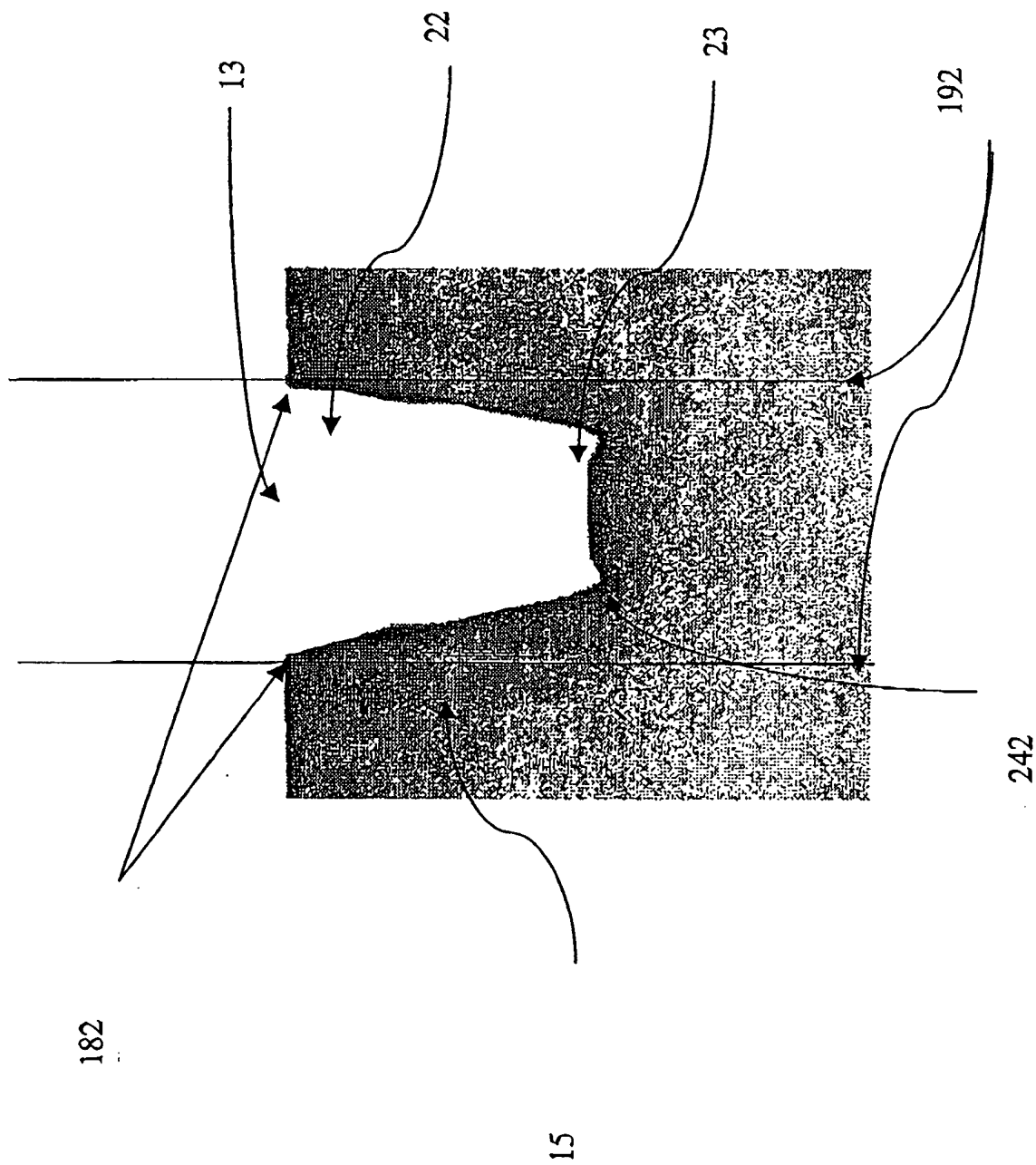


FIGURE 3

FIG. 4 is a cross-sectional view of the device of FIG. 1, taken along the line 4-4 of FIG. 1, showing the internal structure of the device, including the substrate 15, the gate 13, the channel 22, the source 23, and the drain 24. The device is shown in a cross-sectional view, with the substrate 15 at the bottom, the gate 13 on top, and the channel 22, source 23, and drain 24 in the middle. The device is shown in a cross-sectional view, with the substrate 15 at the bottom, the gate 13 on top, and the channel 22, source 23, and drain 24 in the middle.

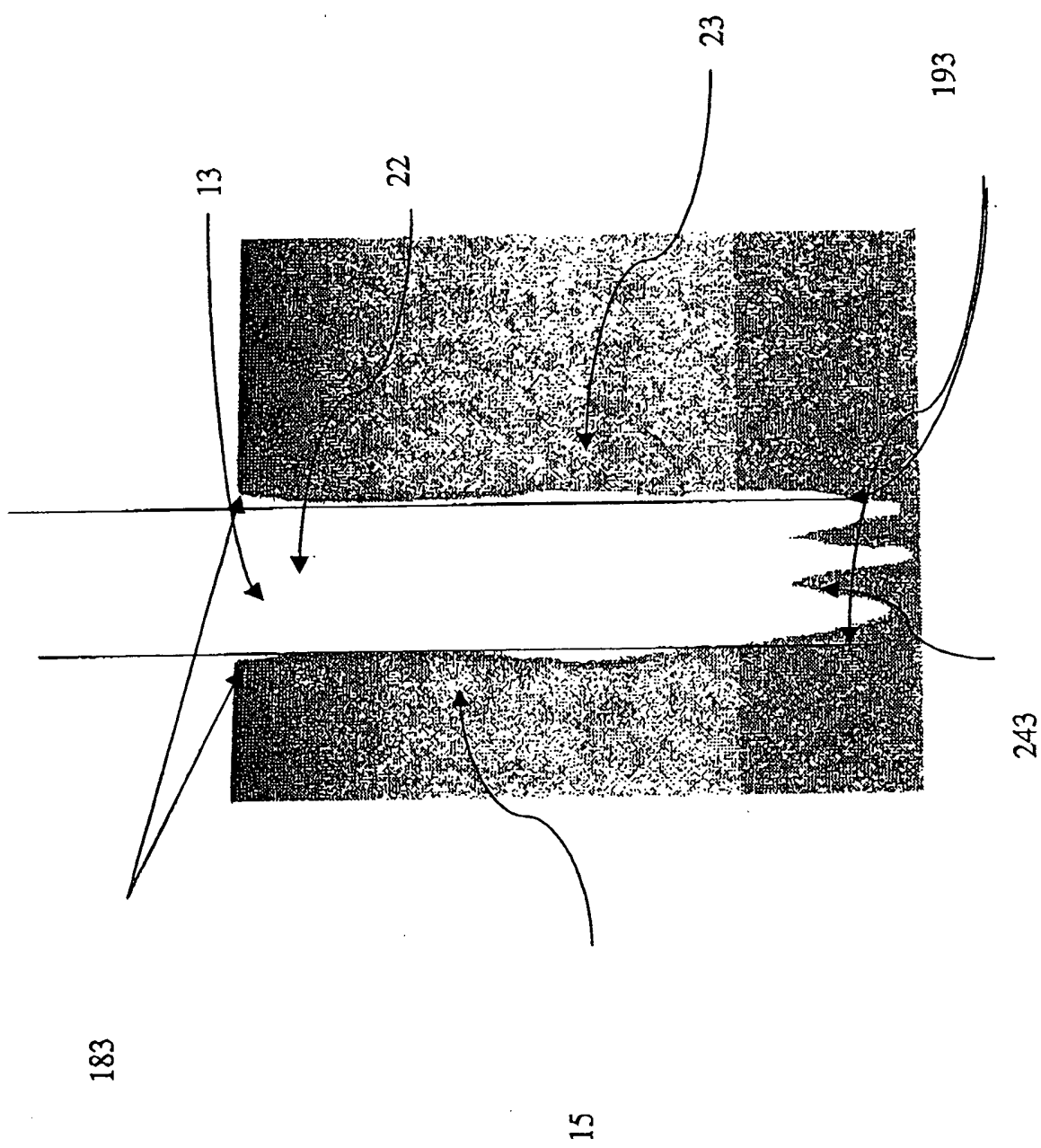


FIGURE 4

FIG. 5 is a schematic diagram of a system for processing a sample in a vacuum chamber. The system includes a sample holder (404) mounted on a support (406) above a vacuum chamber (400). The chamber (400) contains a sample (402) and a processing unit (410) with a control unit (412). The processing unit (410) is connected to a radio frequency (RF) source (RF<sub>2</sub>) via a line (414). The chamber (400) is evacuated by a turbo pump (To Turbo Pump) through a valve (408).

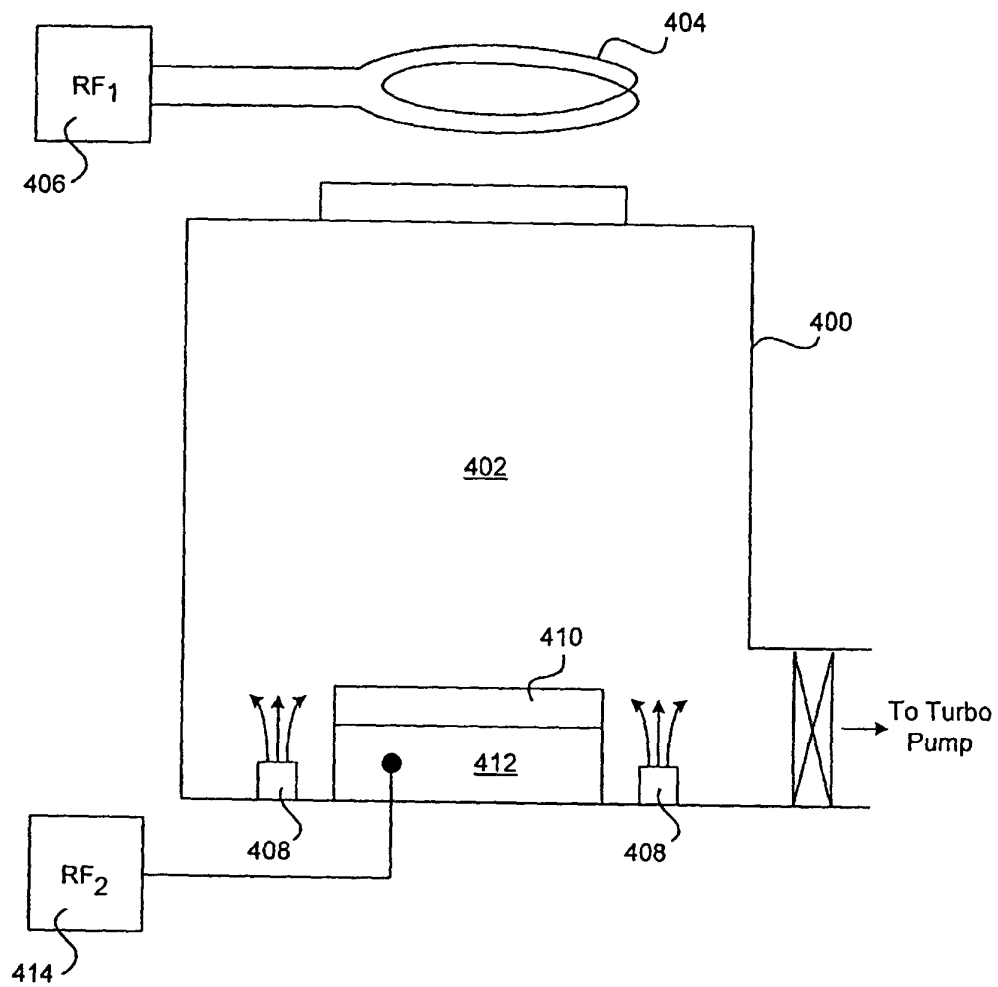


FIGURE 5

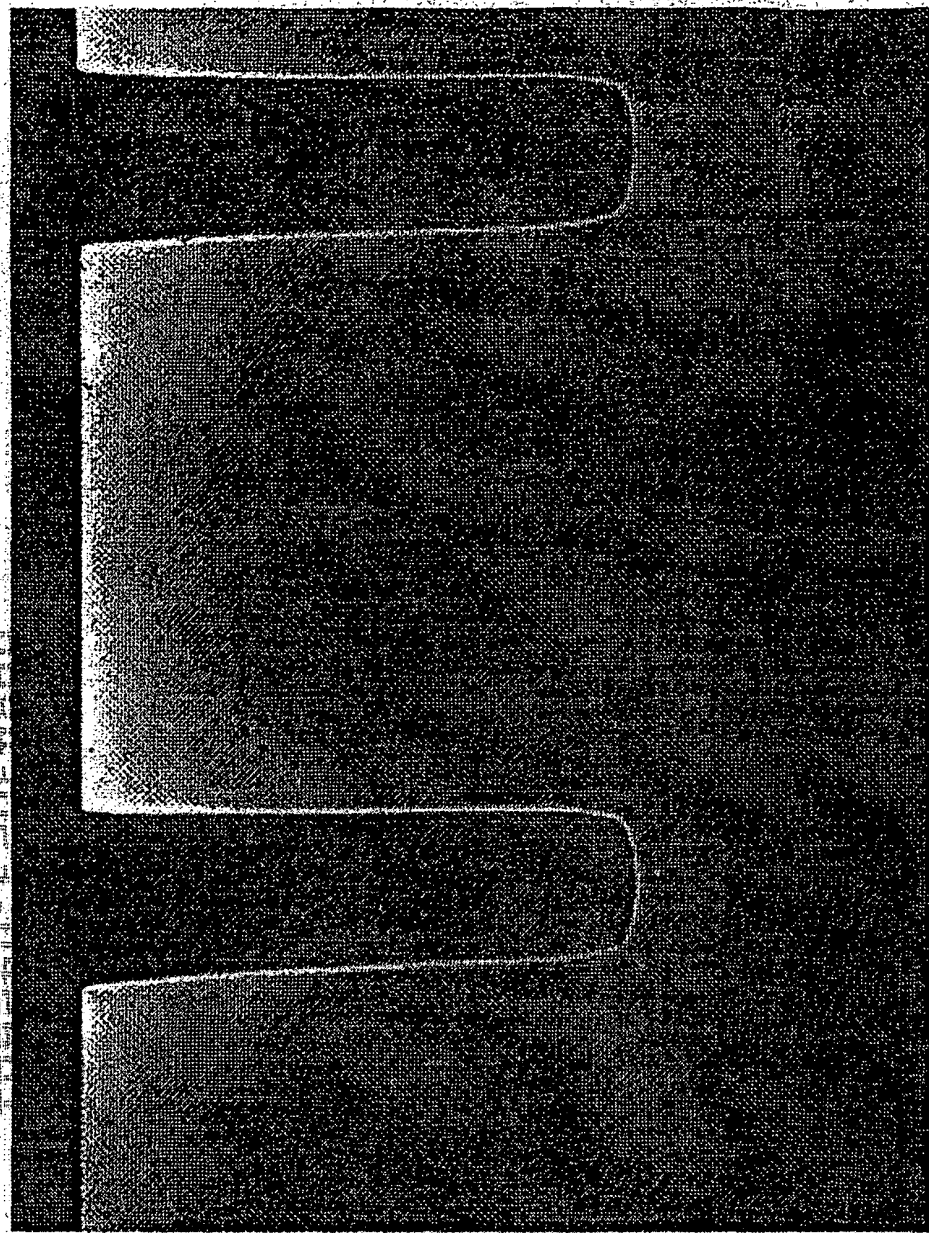


FIGURE 6

Top Corner  
Rounding

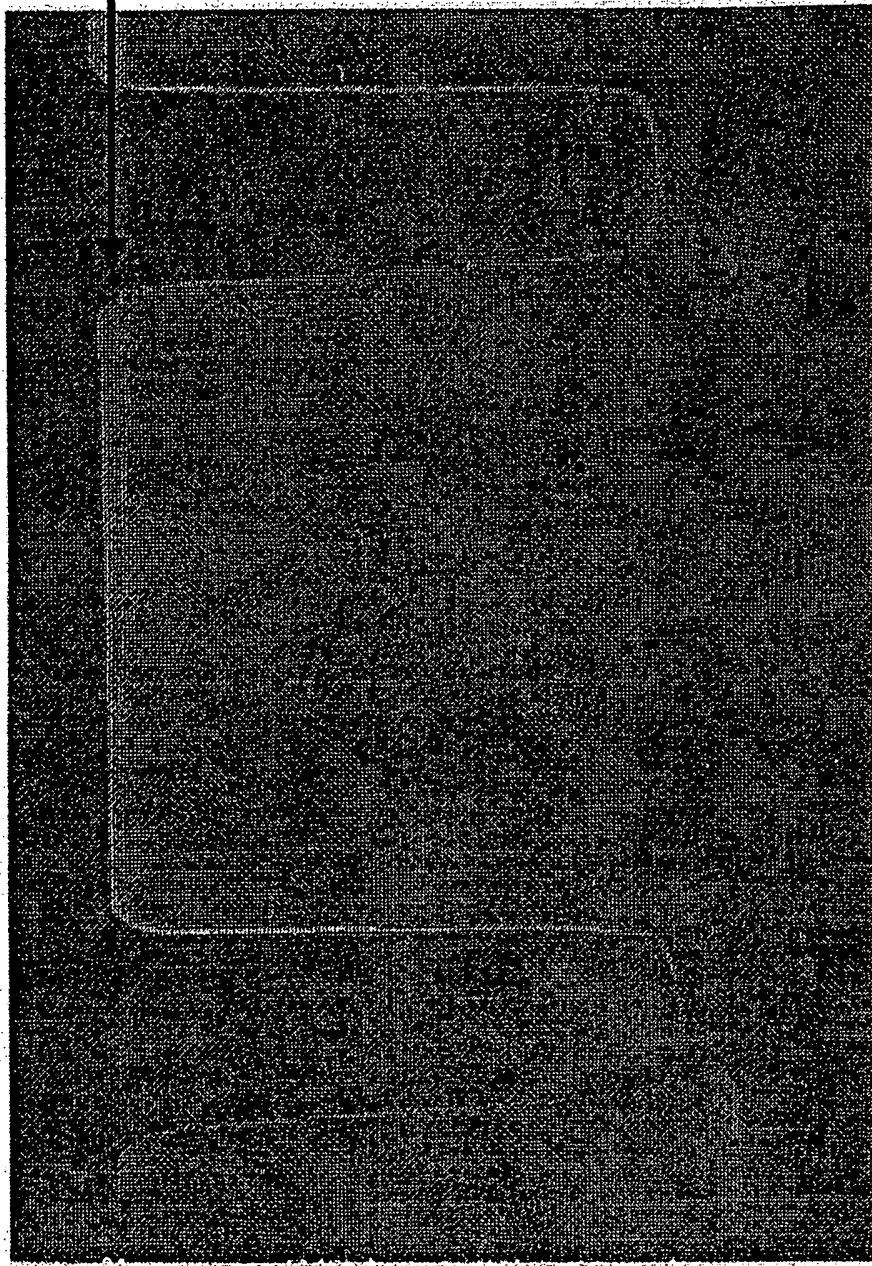


FIGURE 7